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Form 1449*	Atty. Docket No.: 303.648US1	Serial No. 09/484,303
INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use several sheets if necessary)	Applicant: Kie Y. Ahn et al.	
	Filing Date: January 18, 2000	Group: 2823

U.S. PATENT DOCUMENTS

**Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
<u>NB</u>	5,371,042✓	12/06/1994	Ong, E.	437	194	06/16/92
<u>NB</u>	5,413,687✓	05/09/1995	Barton, C.L., et al.	204	192.14	11/27/91
<u>NB</u>	5,962,923✓	10/05/1999	Xu, Z., et al.	257	774	08/07/
<u>NB</u>	6,015,465✓	01/18/2000	Kholodenko, A., et al.	118	719	04/08/98
<u>NB</u>	6,136,095✓	10/24/2000	Xu, Z., et al.	118	719	10/06/97
<u>NB</u>	6,139,699	10/31/2000	Chiang, T., et al.	204	192.15	05/24/97
<u>NB</u>	6,143,646✓	11/07/2000	Wetzel, J.T.	438	637	06/03/97
<u>NB</u>	6,153,507✓	11/28/2000	Mikagi, K.	438	618	01/13/98
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<u>NB</u>	6,183,564✓	02/06/2001	Reynolds, G.J., et al.	118	719	11/12/98
<u>NB</u>	6,271,592✓	08/07/2001	Kim, E., et al.	257	751	08/06/99

FOREIGN PATENT DOCUMENTS

**Examiner Initial	Document Number	Date	Country	Class	Subclass	Translation Yes No
<u>NB</u>	5-267643✓	10/15/1993	Japan			

OTHER DOCUMENTS

**Examiner Initial	(Including Author, Title, Date, Pertinent Pages, Etc.)
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Examiner <u>Neal Berenzny</u>	Date Considered <u>3-22-03</u>
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*Substitute Disclosure Statement Form (PTO-1449)

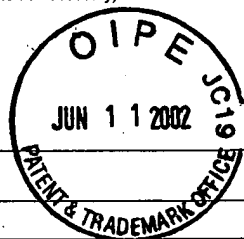
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Complete if Known

Application Number	09/484303
Filing Date	January 18, 2000
First Named Inventor	Ahn, Kie
Group Art Unit	2825
Examiner Name	Unknown

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Attorney Docket No: 00303.648US1

US PATENT DOCUMENTS

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<i>nb</i>	US-5609721 ✓	03/11/1997	Tsukune, A, et al	156	646.1	01/03/1995
<i>nb</i>	US-5907772 ✓	05/25/1999	Iwasaki, Haruo	438	253	02/26/1997
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Examiner Initials*	Foreign Document No	Publication Date	Name of Patentee or Applicant of cited Document	Class	Subclass	T ²
<i>nb</i>	JP-07-321111 ✓	08/12/1995	Tetsuo, K.	H01L	21/3205	

OTHER DOCUMENTS -- NON PATENT LITERATURE DOCUMENTS

Examiner Initials*	Cite No ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
<i>nb</i>		EISENBRAUN, E.T., et al., "Selective and Blanket Low-Temperature Copper CVD for Multilevel Metallization in ULSI", <u>Conference Proceedings ULSI-VII</u> , (1992), 5 pages ✓	
<i>nb</i>		KALOYEROS, A.E., et al., "Blanket and Selective Copper CVD from Cu(FOD) ₂ for Multilevel Metallization", <u>Mat. Res. Soc. Symp. Proc.</u> , Vol. 181, (1990), 6 pages ✓	
<i>nb</i>		KLAUS, J.W., "Atomic Layer Deposition of Tungsten Nitride Films Using Sequential Surface Reactions", <u>Journal of the Electrochemical Society</u> , 147(3), (2000), pp. 1175-1181 ✓	
<i>nb</i>		MIN, JAE-SIK., "Metal-Organic Atomic-Layer Deposition of Titanium-Silicon-Nitride Films", <u>Applied Physics Letters</u> , Volume 75, No. 11, (1999), pp. 1521-1523 ✓	

EXAMINER

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